

Notice of References Cited

Application/Control No.

09/827,056

Applicant(s)/Patent Under
Reexamination
LIU ET AL.

Examiner

Thomas J. Magee

Art Unit

2811

Page 1 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,355,527	03-2002	Yai-Fen Lin et al.	438/265
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Stanley Wolf, "Silicon Processing for the VLSI Era, Vol. 2," Lattice Press, Sunset Beach, Ca., (1990), pp. 321-322.
	V	Tomohisa Mizuno, Shizuo Sawada, Yoshikazu Saitoh, and Takeshi Tanaka, "Hot-Carrier Injection Suppression Due to the Nitride-Oxide LDD Spacer Structure," IEEE Trans. on Electron Devices, Vol.38, No. 3, (1991), pp. 584-591.
	W	Syd R. Wilson, Clarence J. Tracy, and John L. Freeman, Jr., "Handbook of Multilevel Metallization for Integrated Circuits," Noyes Publ., Westwood, New Jersey, (1993), p. 868.
	X	S.M. Sze, "Physics of Semiconductor Devices," John Wiley & Sons, New York (1981), p. 68.

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

Notice of References Cited

Application/Control No.

09/827,056

Applicant(s)/Patent Under
Reexamination
LIU ET AL.

Examiner

Thomas J. Magee

Art Unit

2811

Page 2 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	<input checked="" type="checkbox"/>	S. Wolf and R.N. Tauber, "Silicon Processing for the VLSI Era, Volume 1: Process Technology," Lattice Press, Sunset Beach, CA. (1986), pp.321 - 322.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.